



Title: MOCVD PROCESS USING OZONE AS A REACTANT TO
DEPOSIT A METAL OXIDE BARRIER LAYER
Inventor: David A. Cathey and Trung T. Doan
Docket No.: 11675.23

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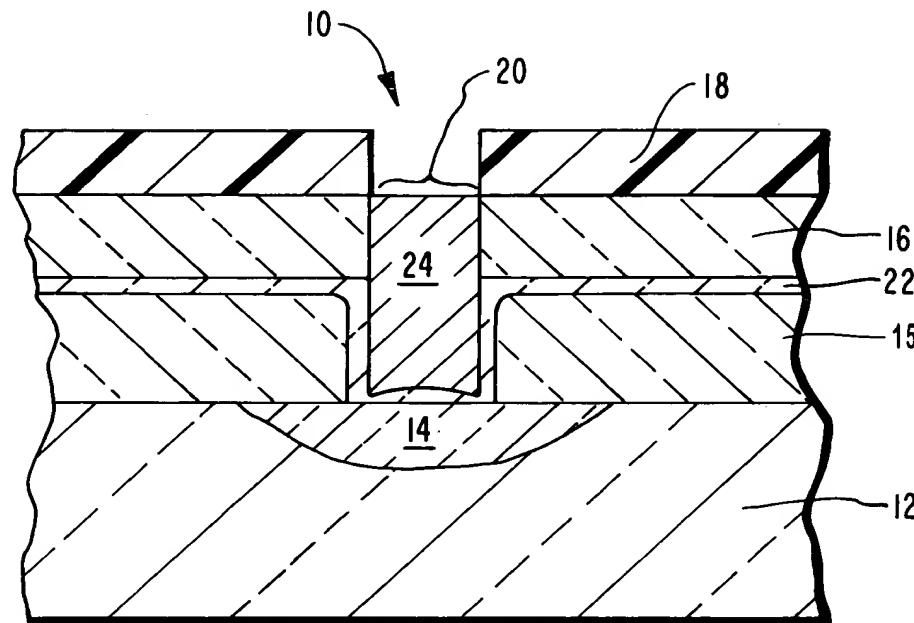


FIG. 1

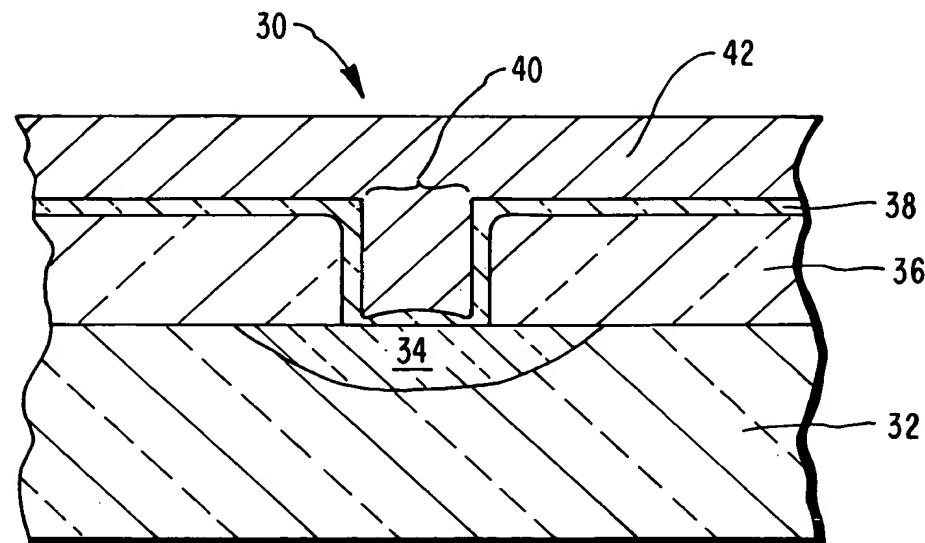


FIG. 2

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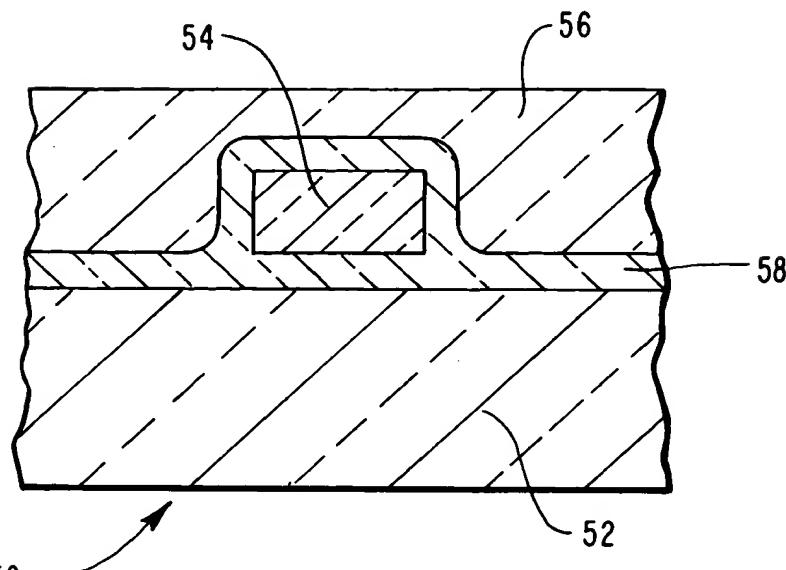


FIG. 3

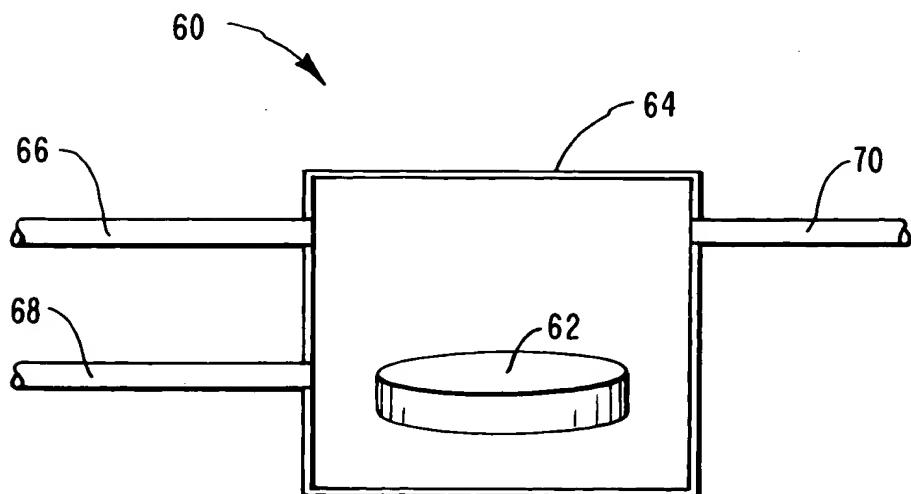


FIG. 4